

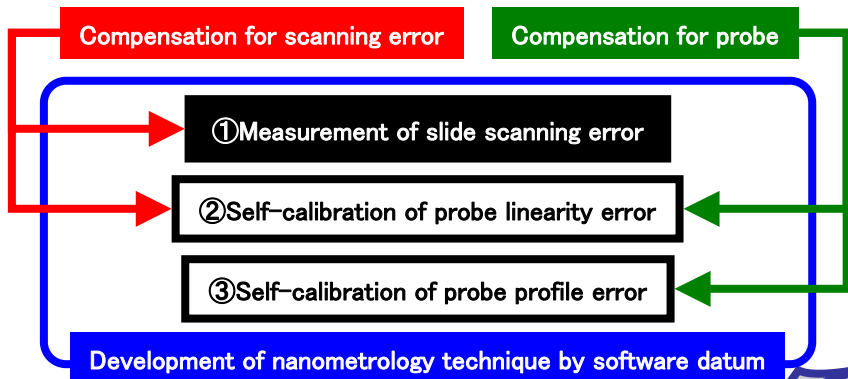
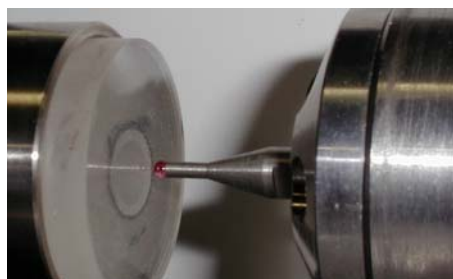
Study on nanometrology of aspherical profile

JPPN 2003-279345

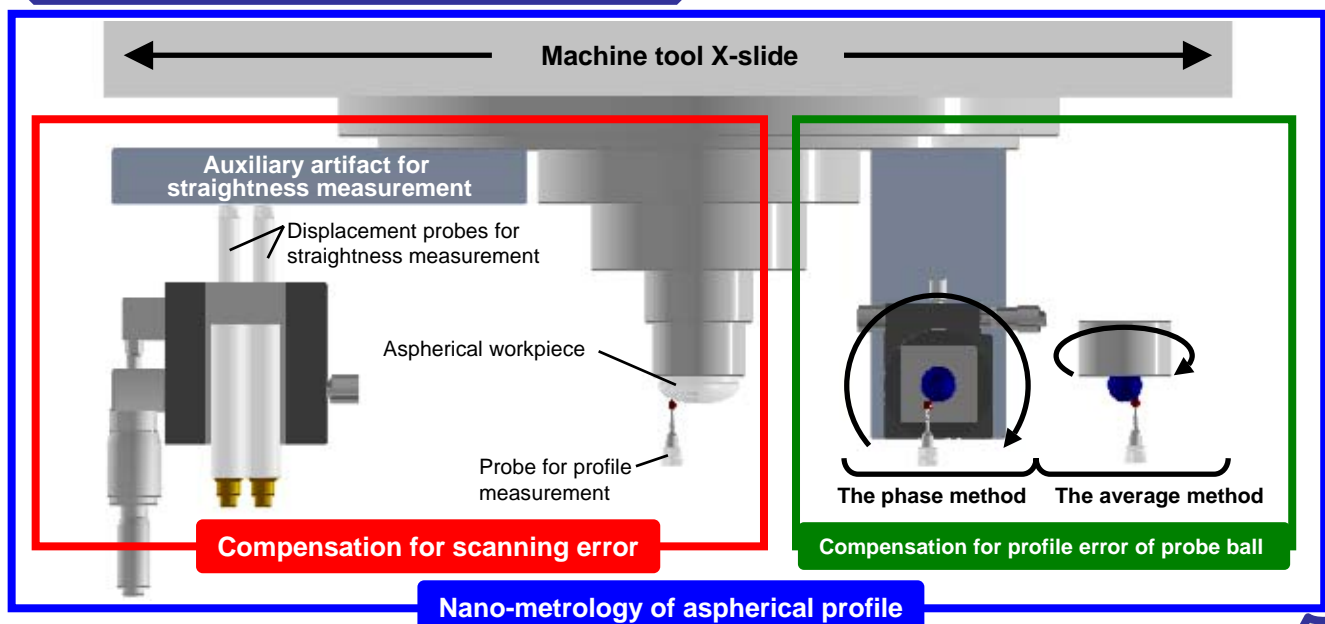
Background

Motivation Realization of Highly accurate aspherics [Accuracy requirement : under 50nm]

Research problem



On-machine measurement system



Experimental results

